

20054352 011802

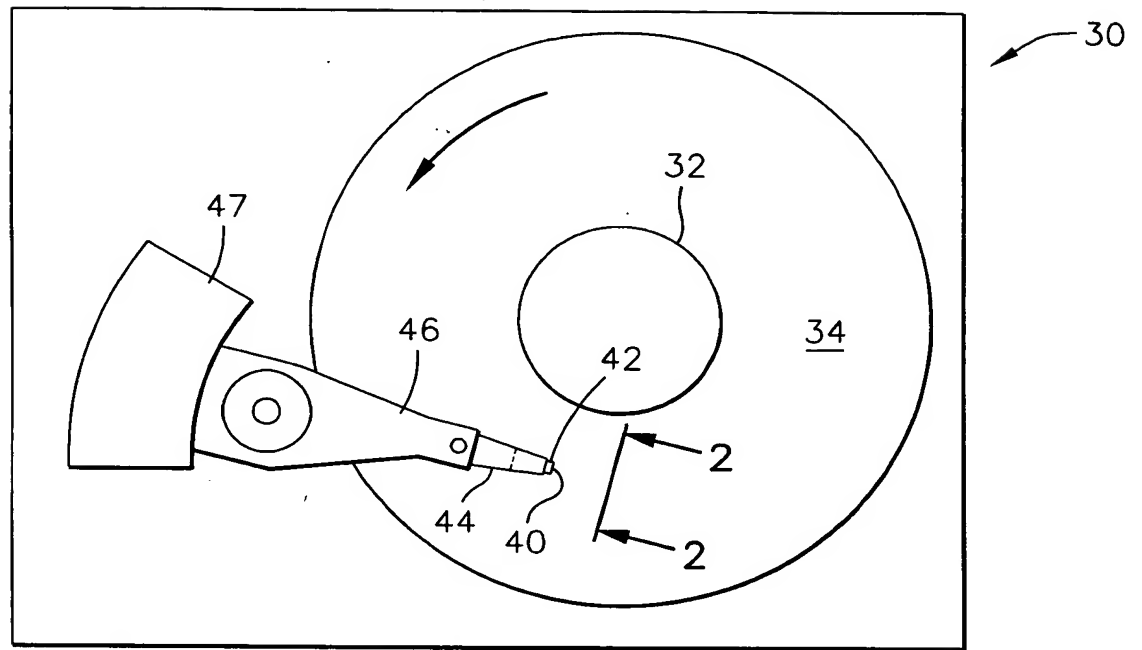


FIG. 1

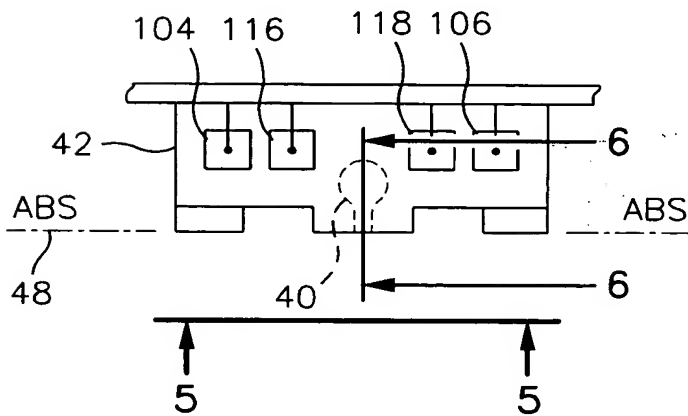


FIG. 2

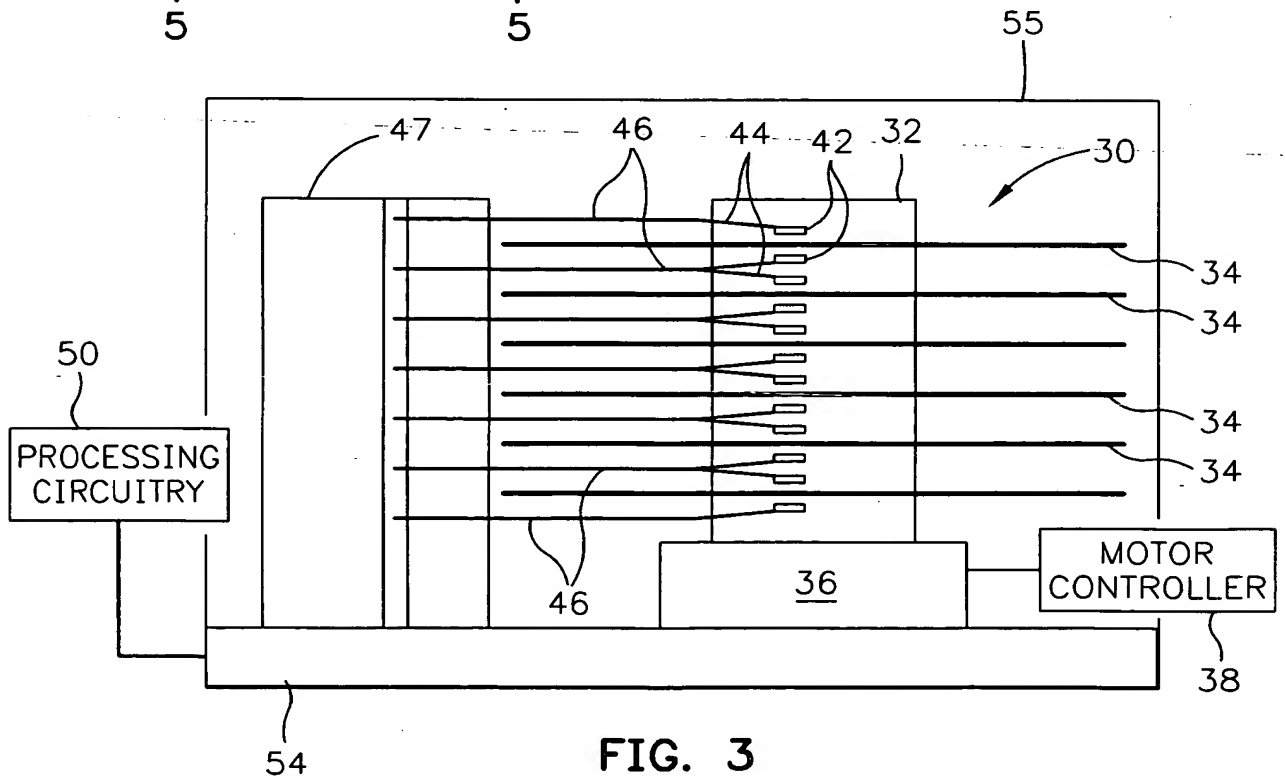


FIG. 3

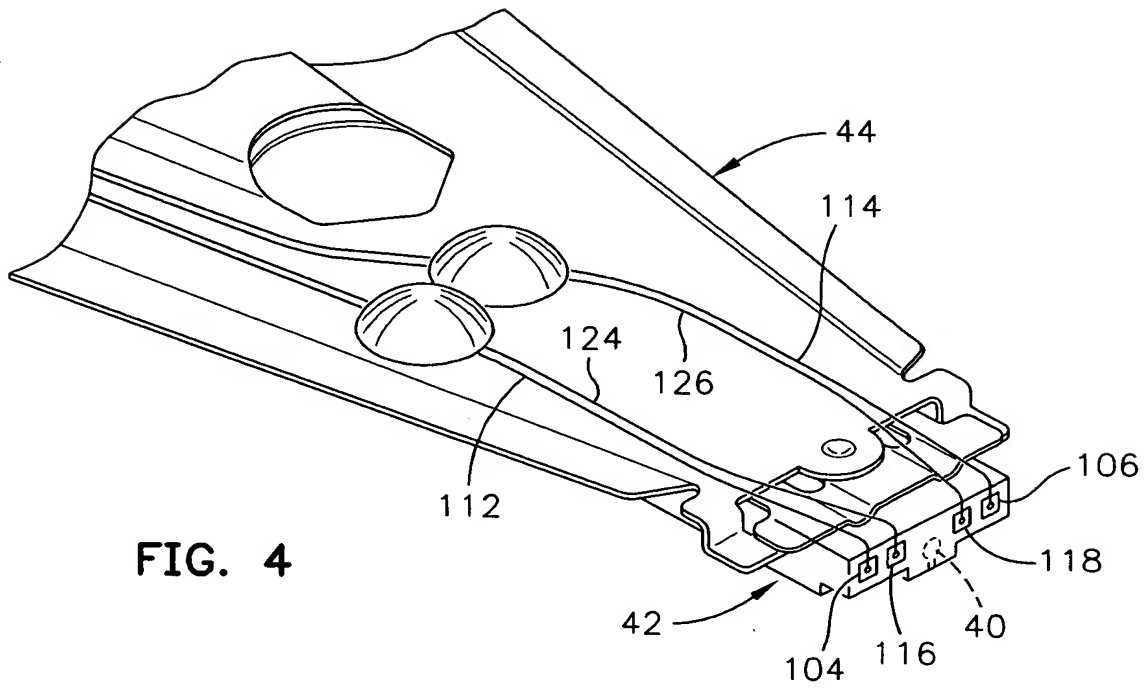


FIG. 4

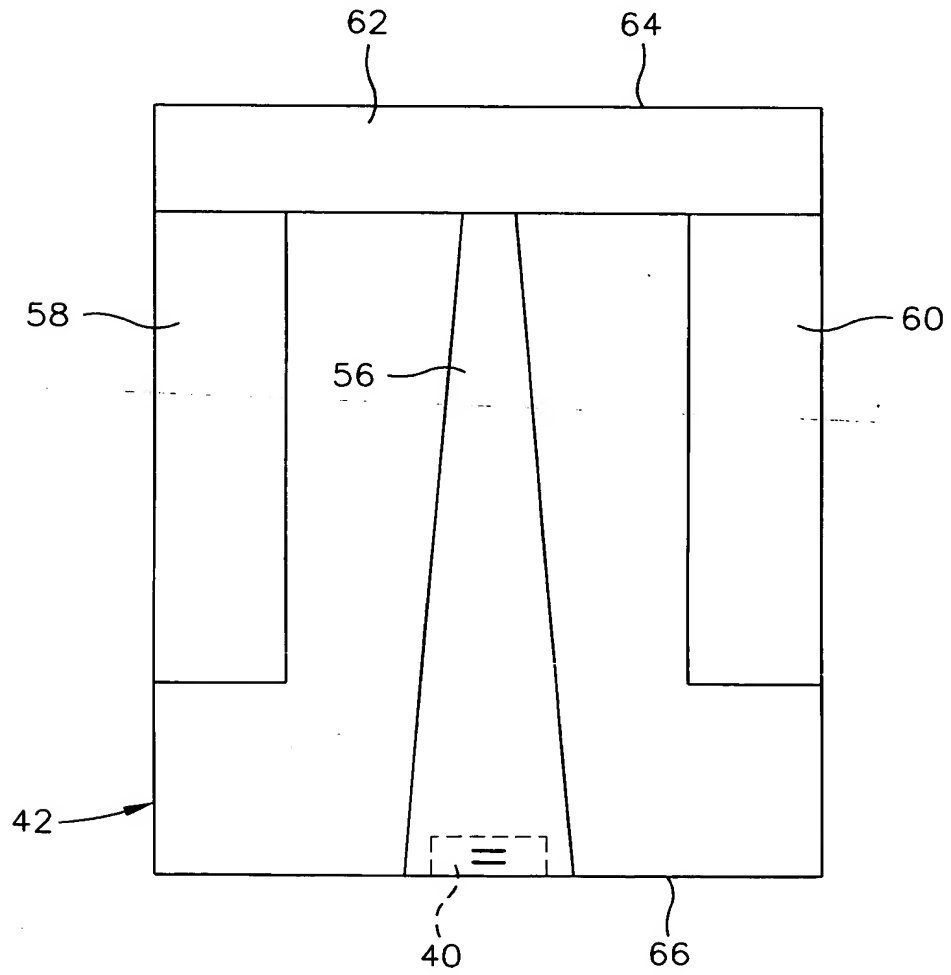
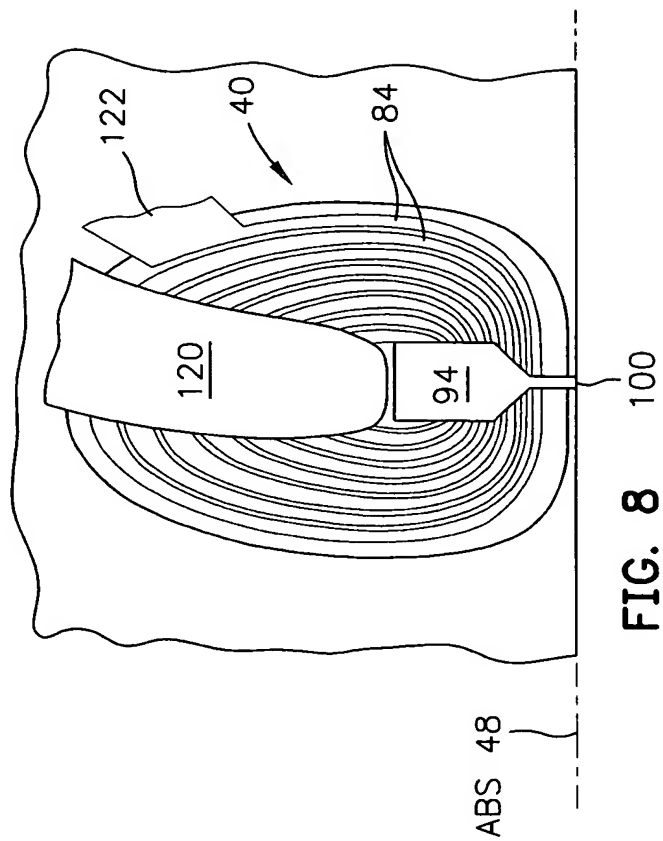
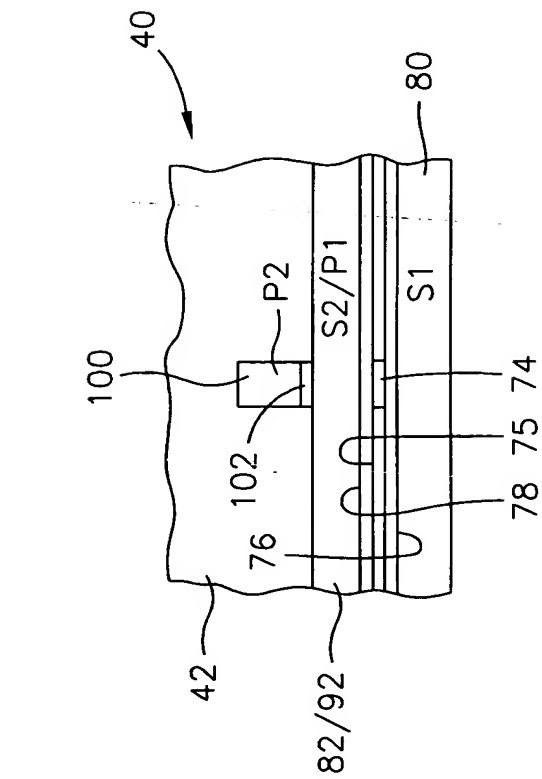


FIG. 5



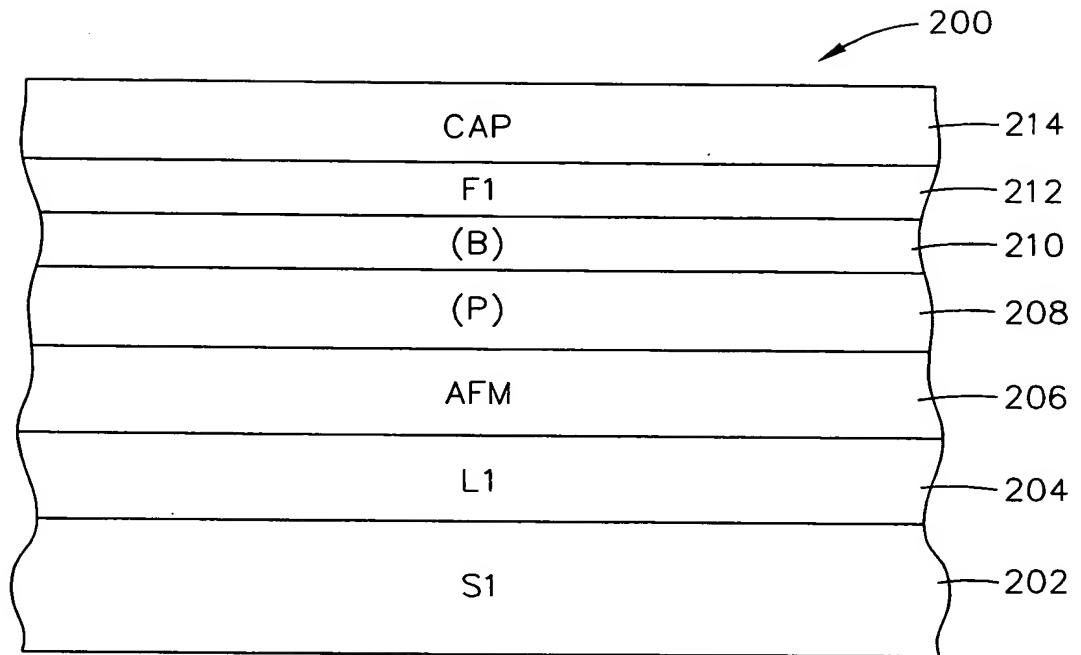


FIG. 9

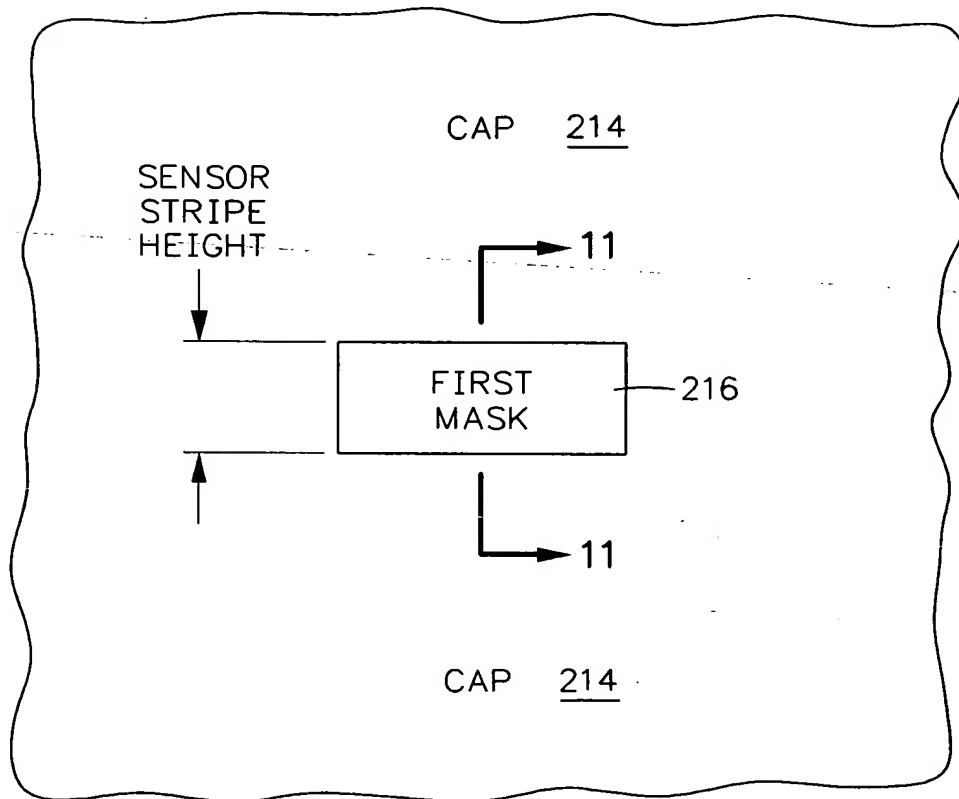


FIG. 10

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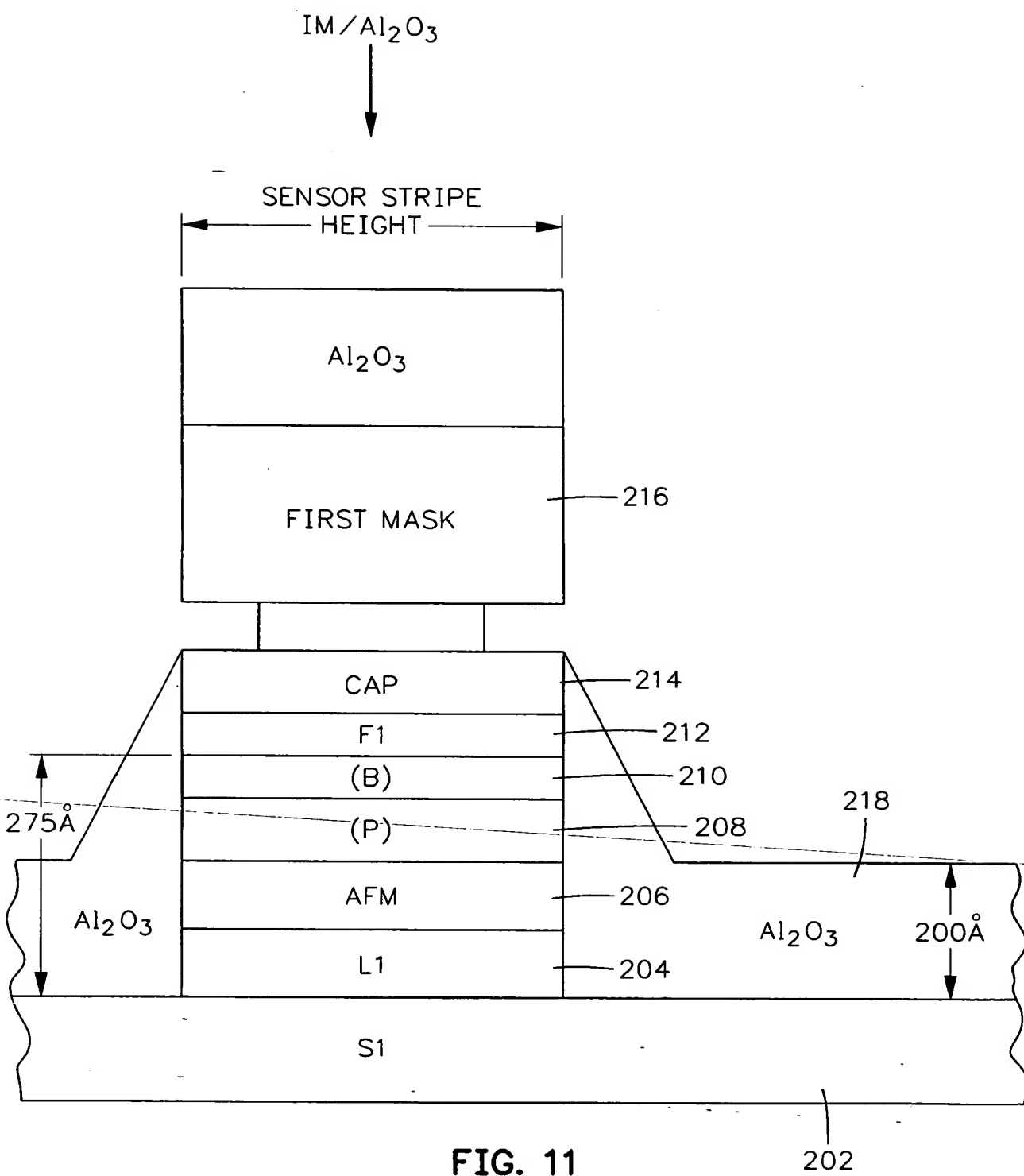


FIG. 11

REMOVE 1ST MASK AND SPUTTER ETCH AWAY CAP

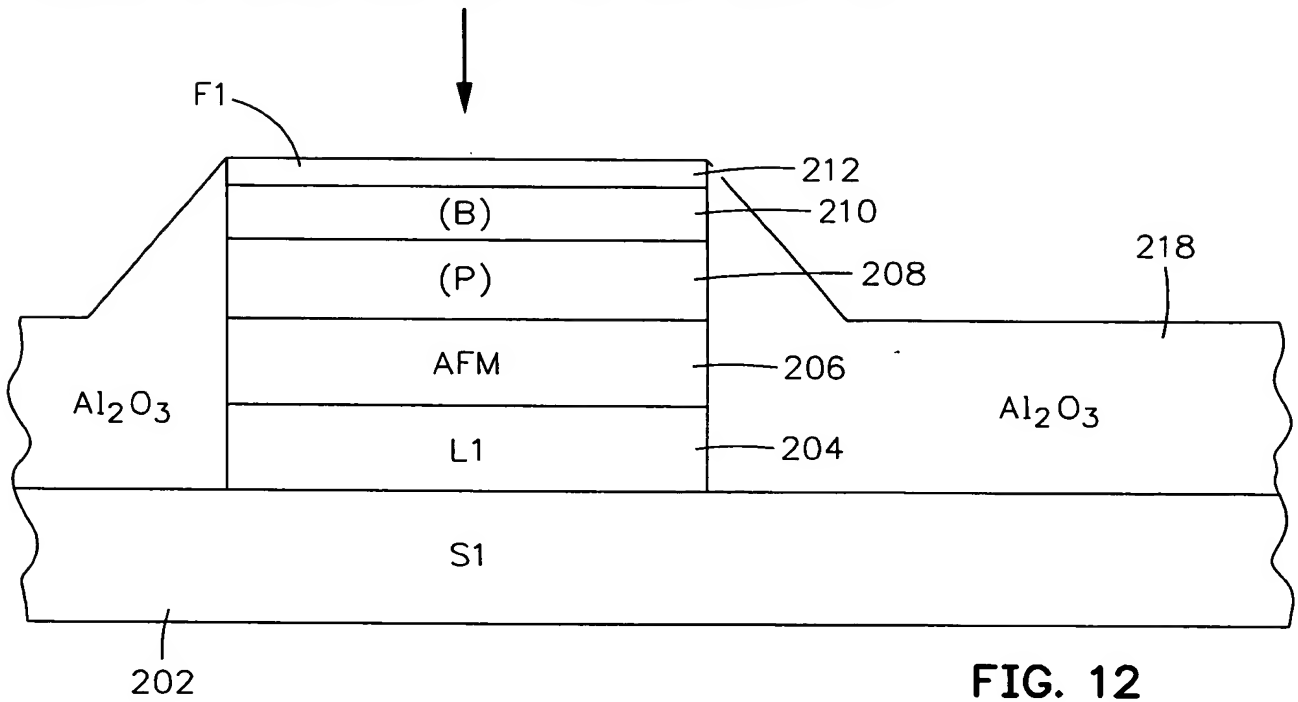


FIG. 12

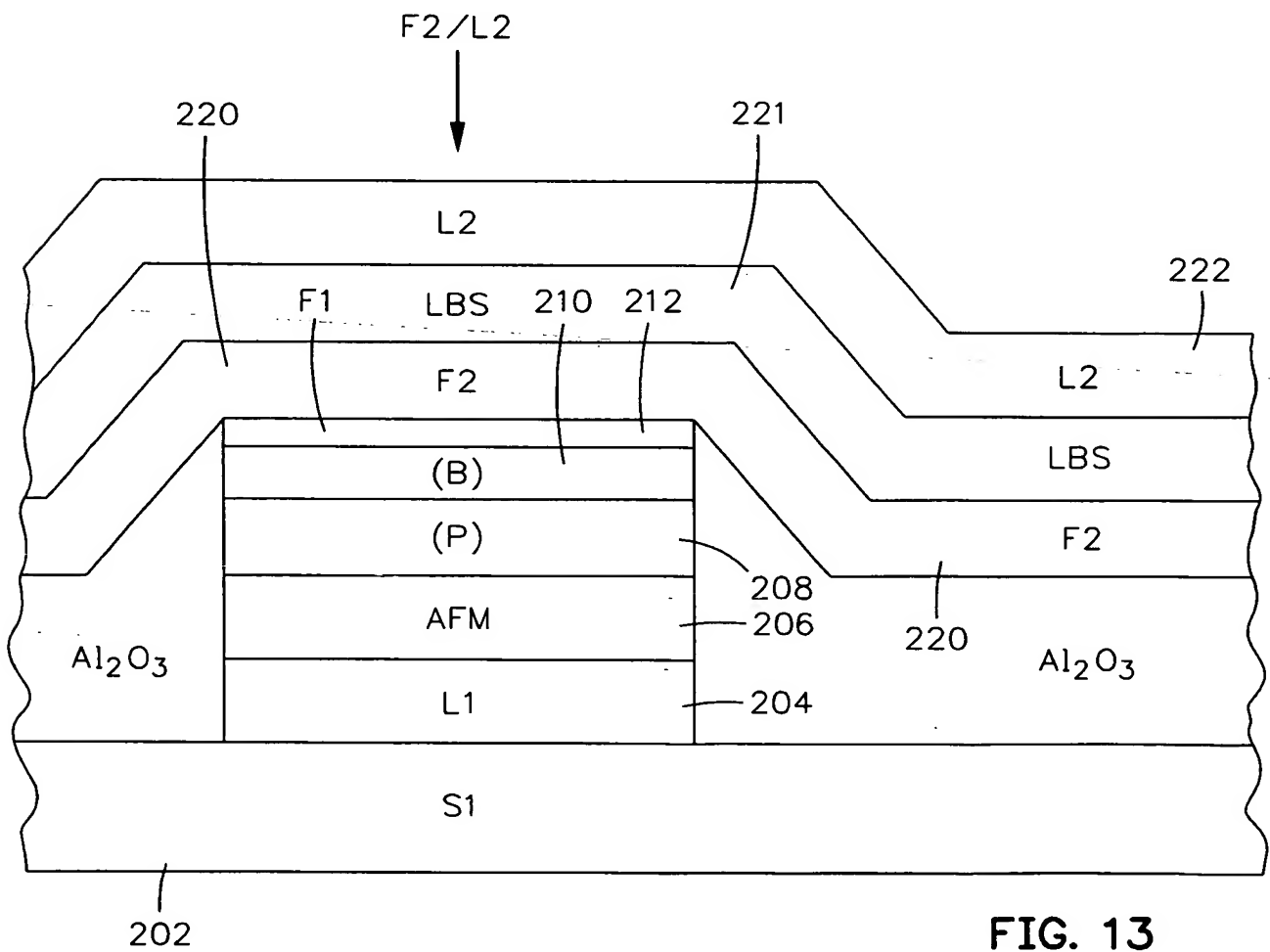


FIG. 13

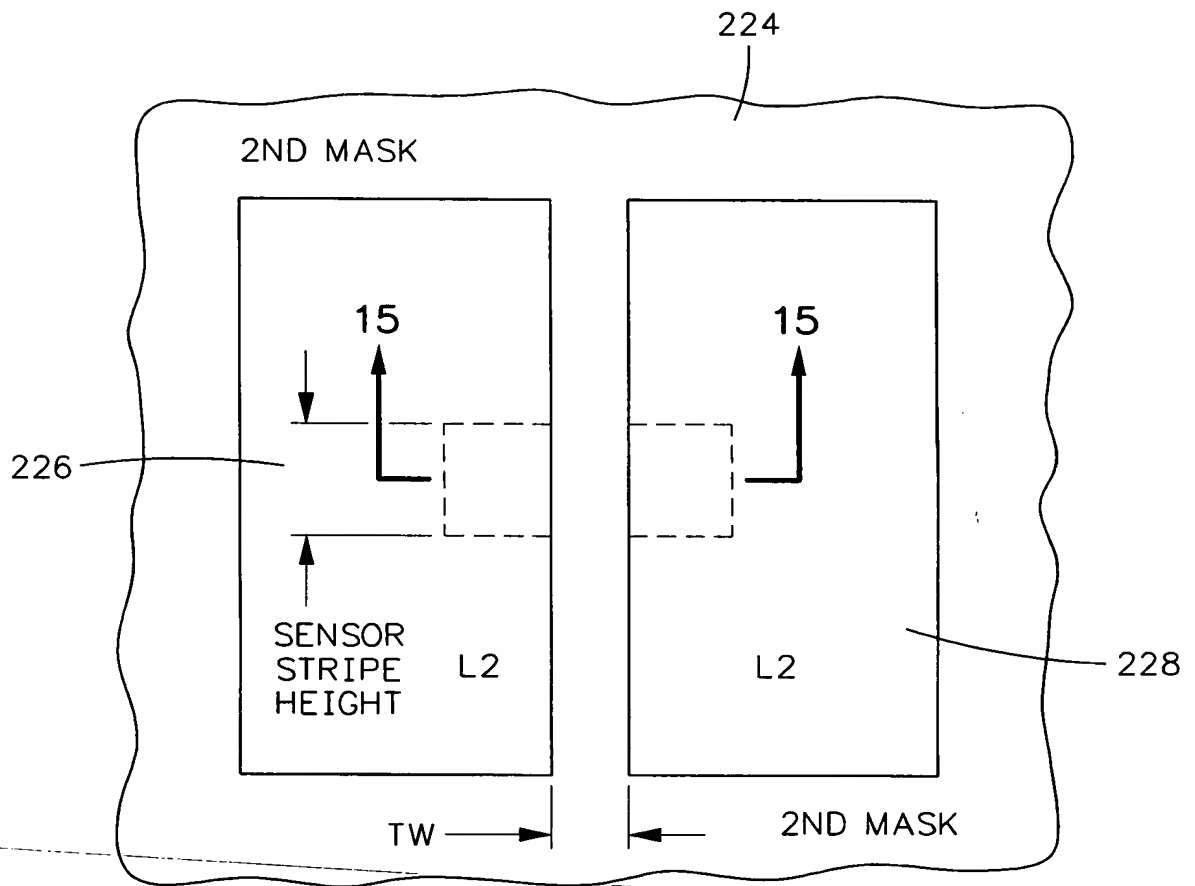


FIG. 14

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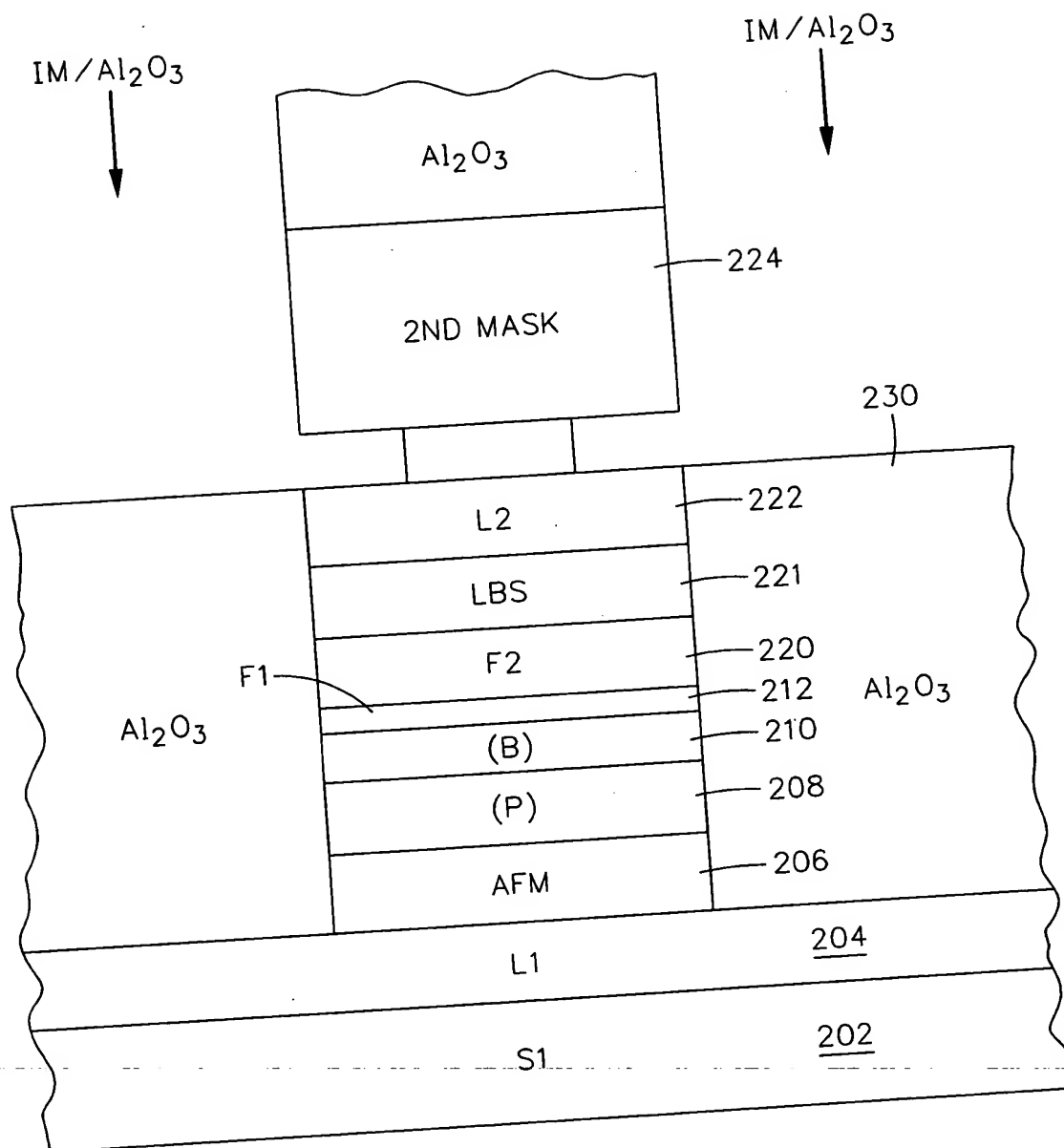


FIG. 15

REMOVE 2ND MASK  
DEPOSIT S2

FIG. 16



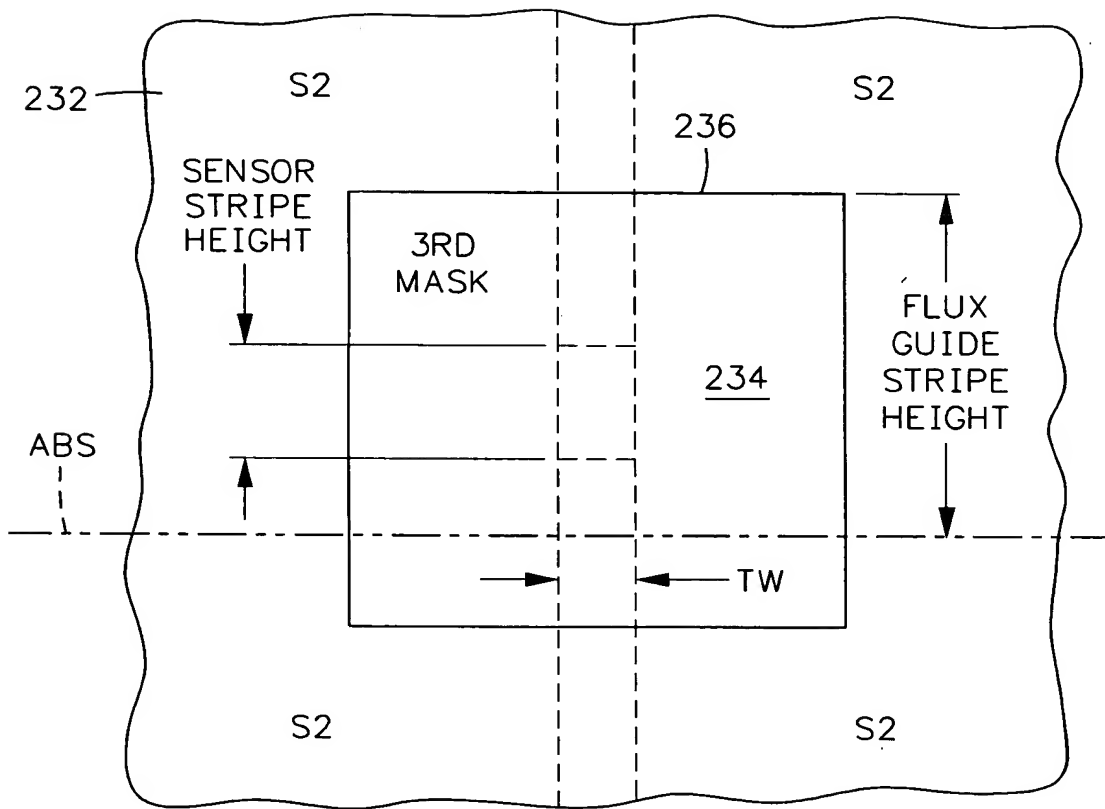


FIG. 17

ION MILL  
REMOVE 3RD MASK

FIG. 18

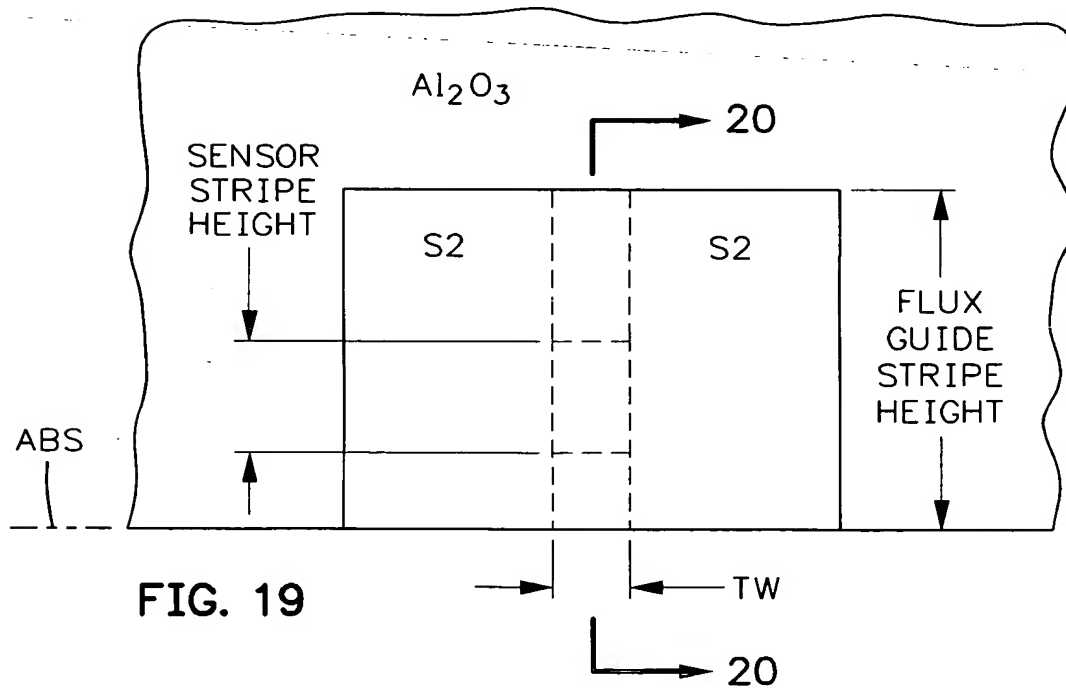


FIG. 19

20254350.01800

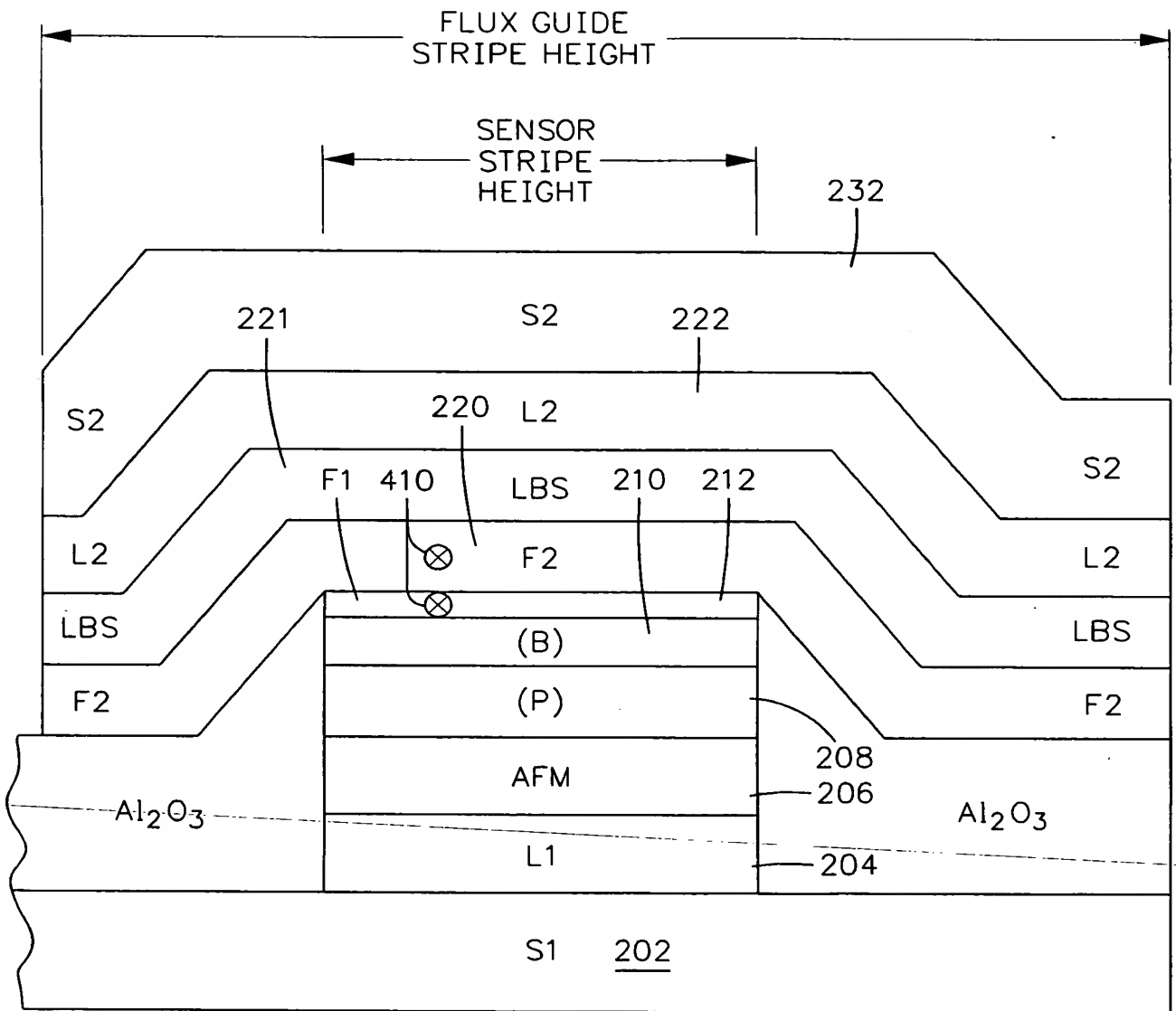
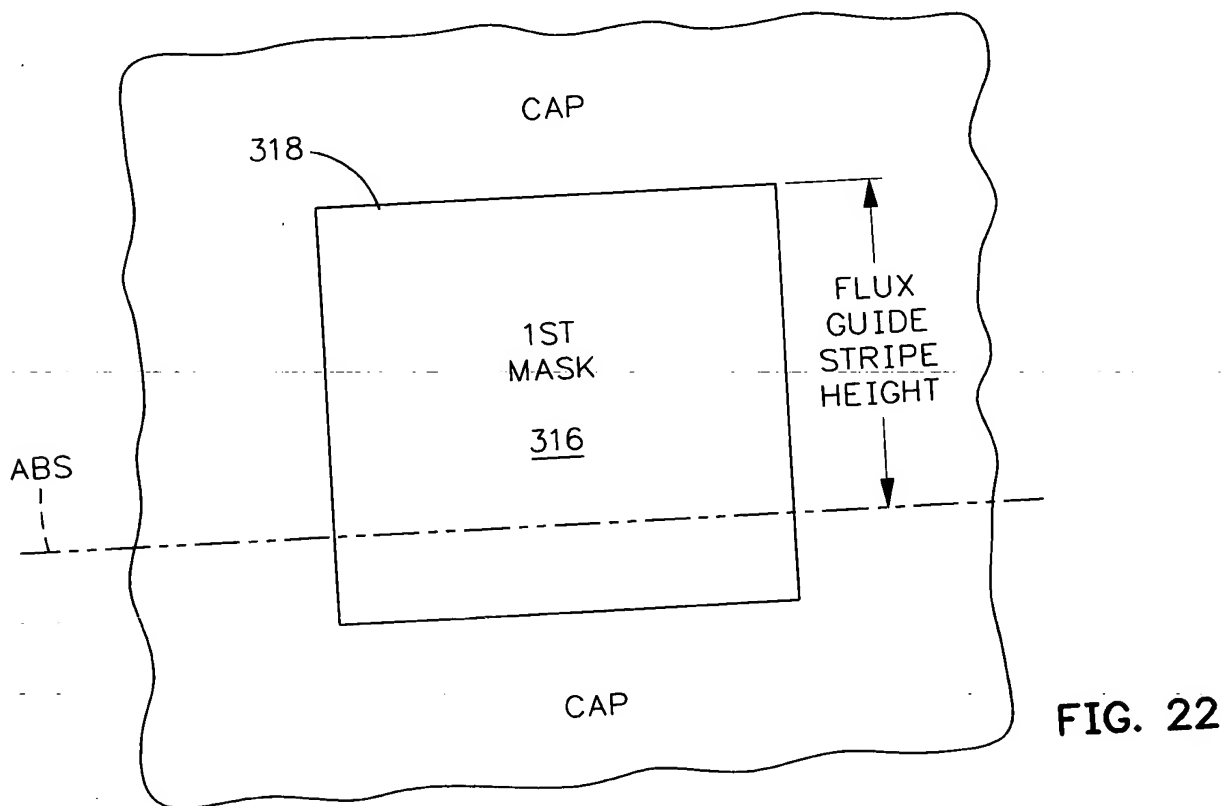
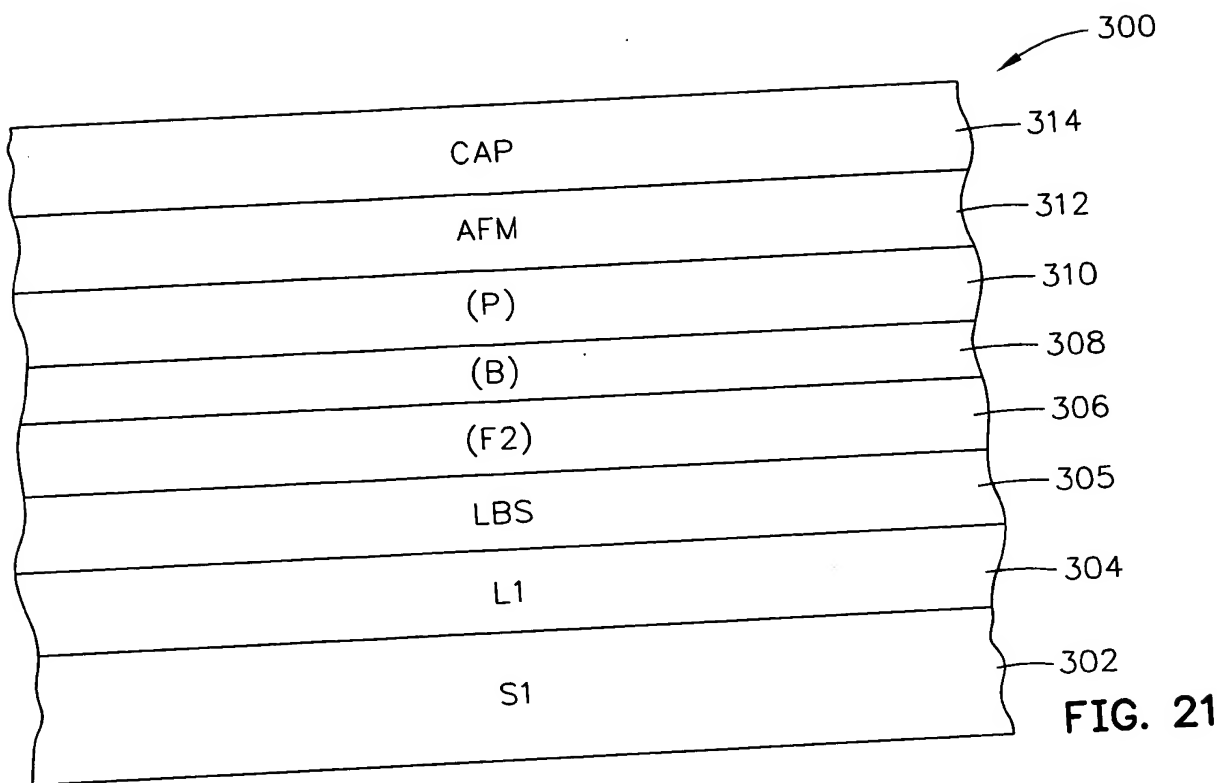


FIG. 20

20254332.01802



ION MILL CAP  
DEPOSIT ALUMINA  
REMOVE 1ST MASK

FIG. 23

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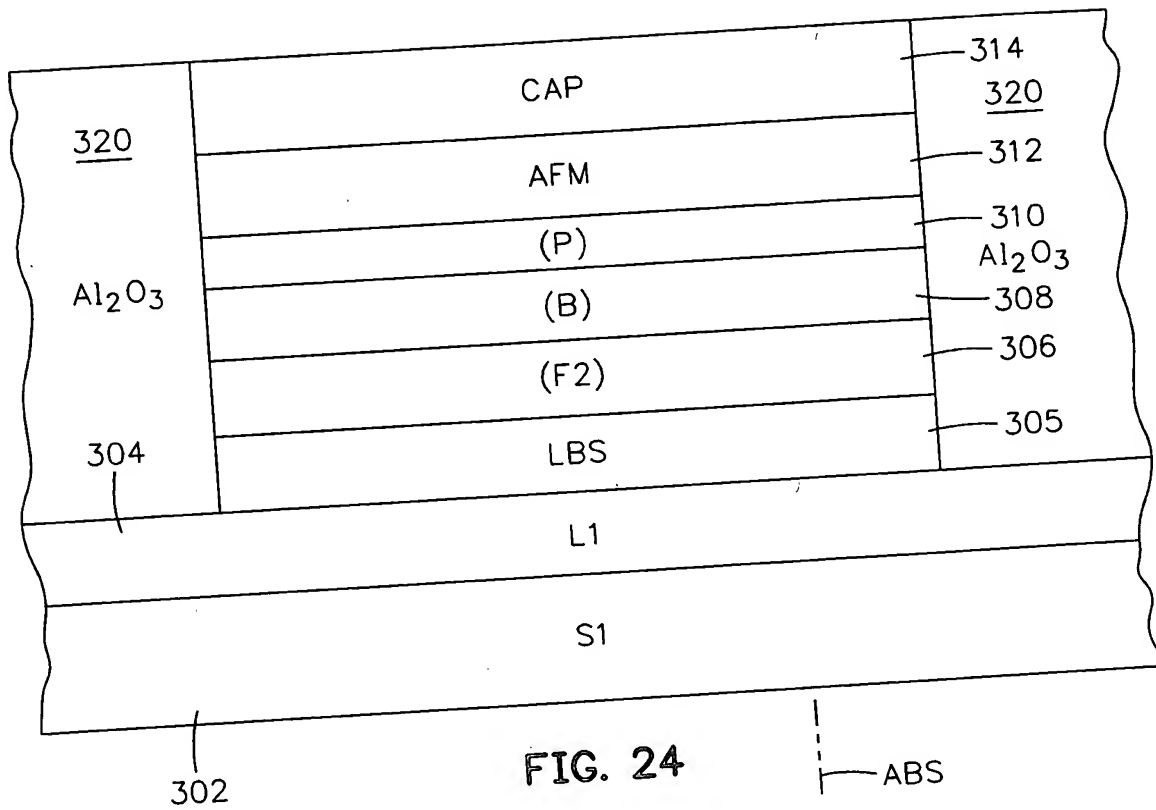


FIG. 24

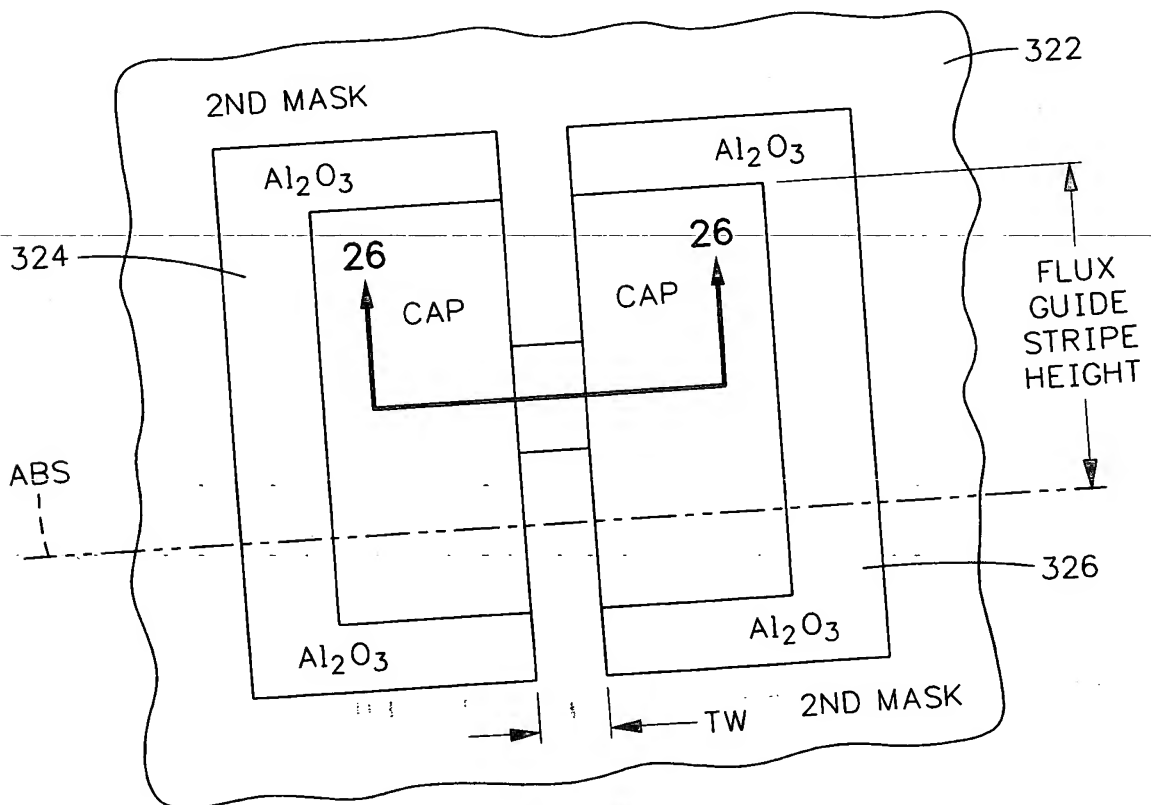


FIG. 25

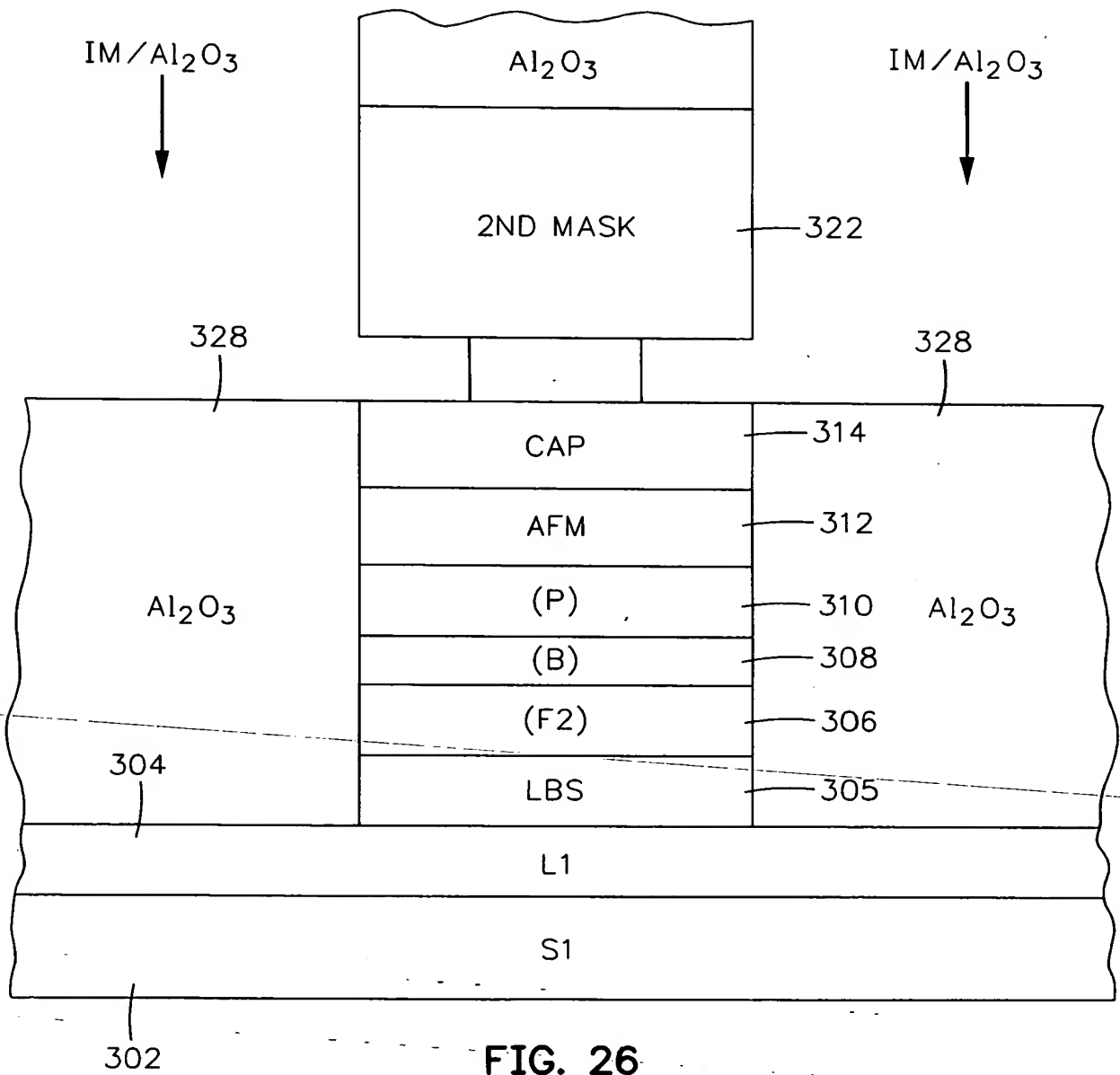


FIG. 26

10054352 011802

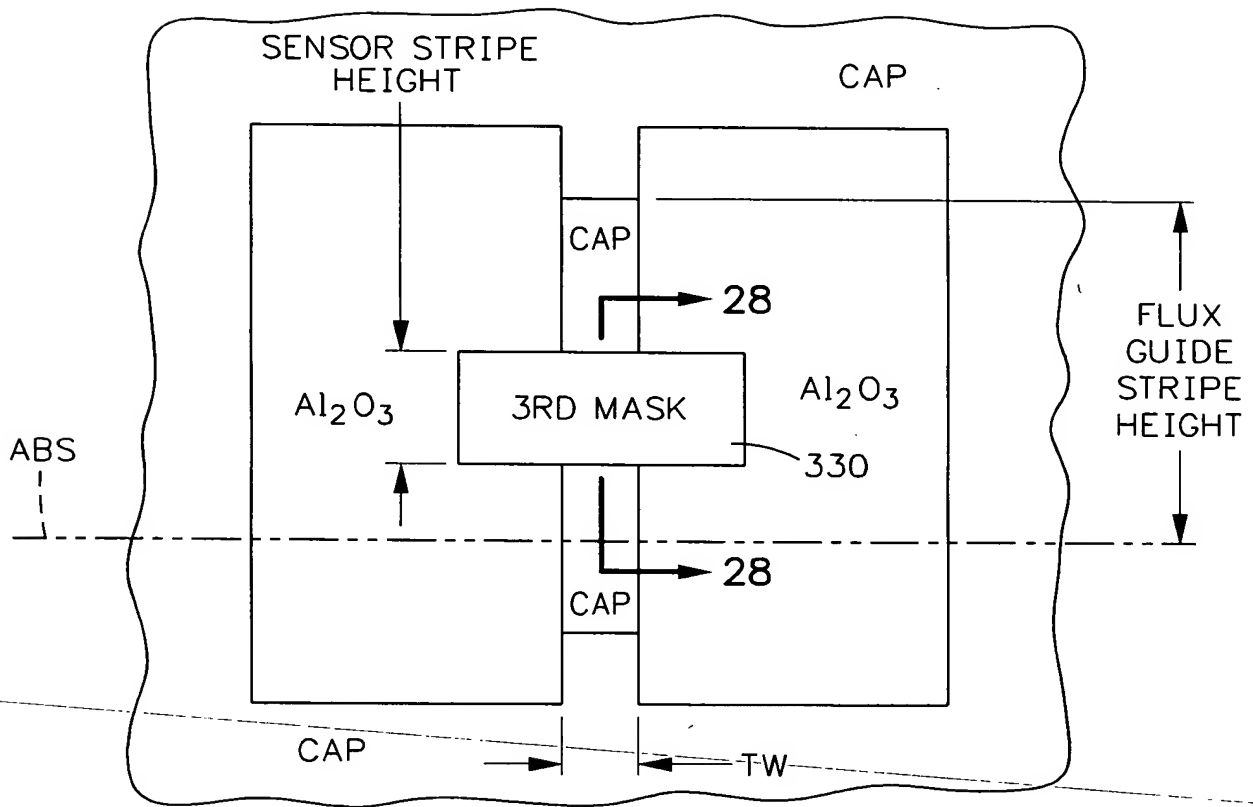


FIG. 27

20081011 011800

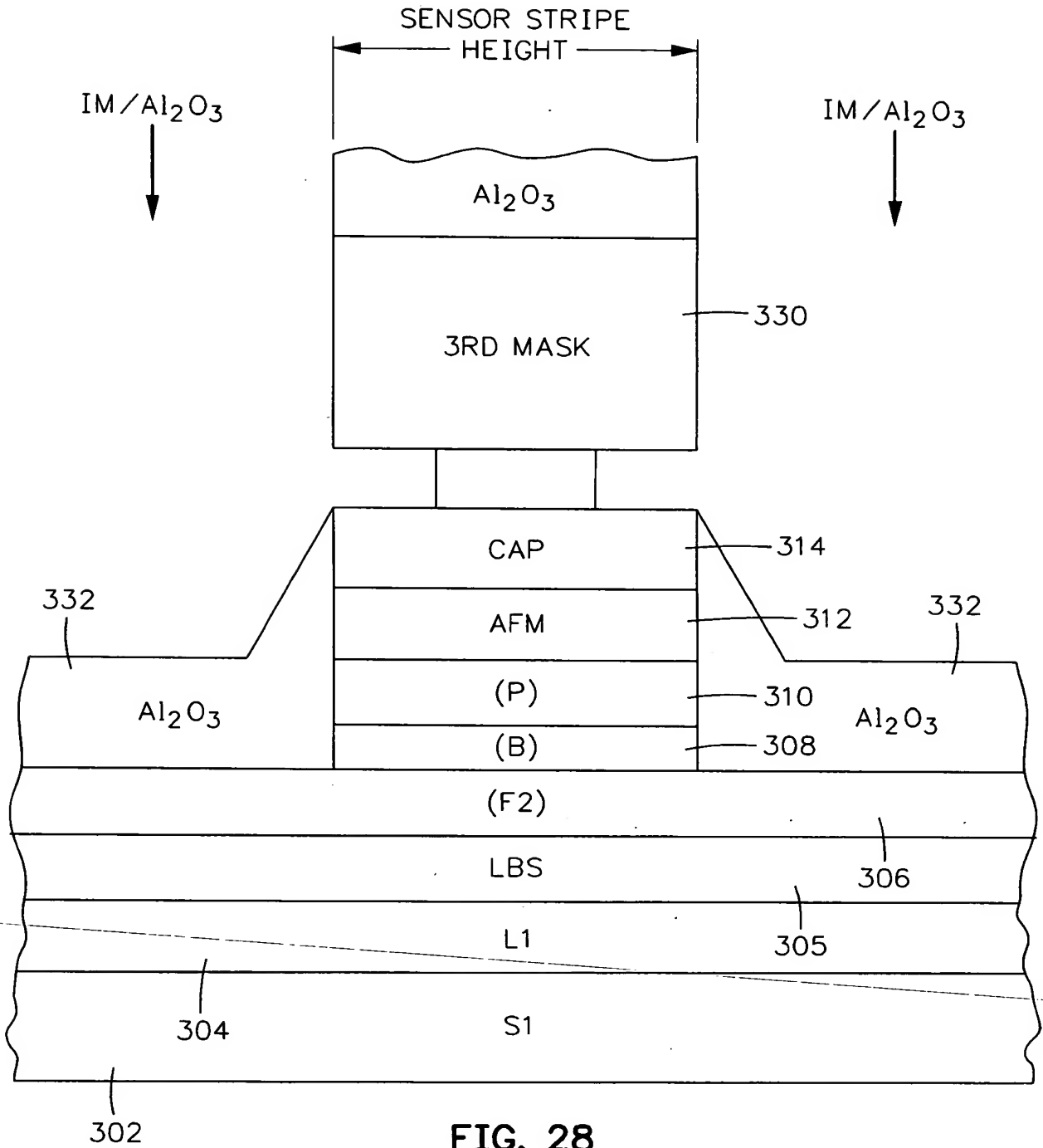
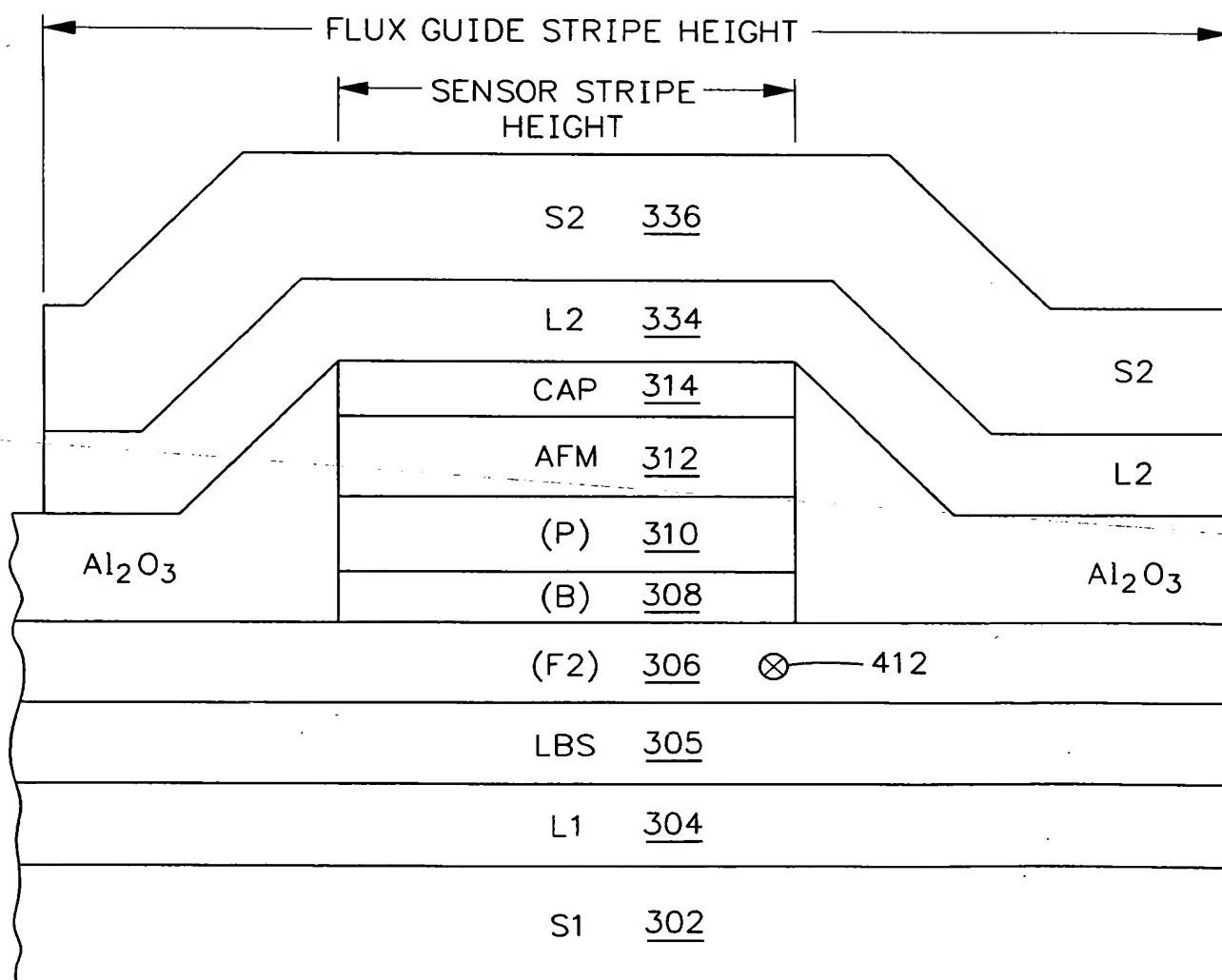
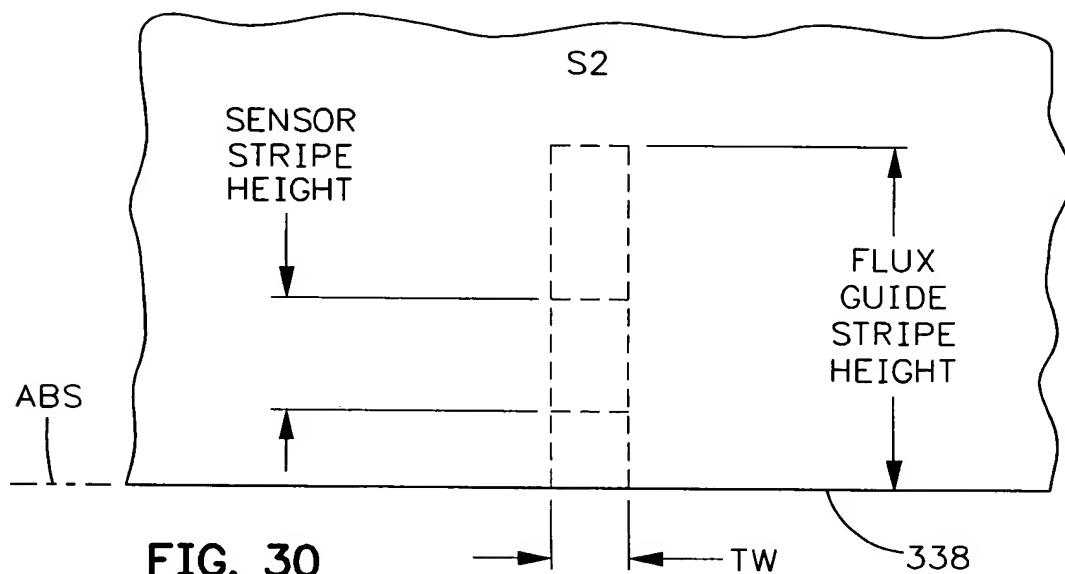


FIG. 28

REMOVE 3RD MASK  
DEPOSIT L2/S2

FIG. 29





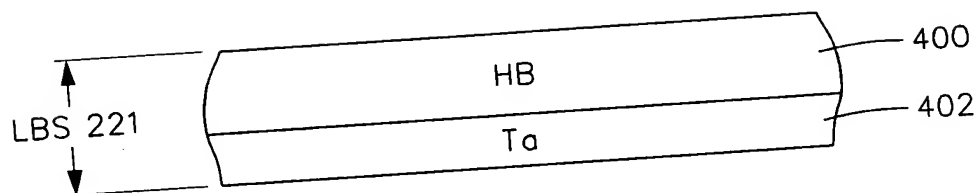


FIG. 32



FIG. 33

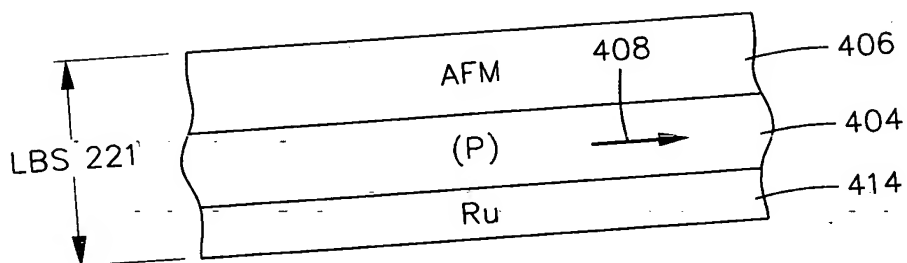


FIG. 34

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